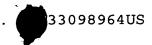
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## Abstract of the Invention

A cleaning system for cleaning boxes or containers used to carry semiconductor wafers has box holder assemblies attached to a rotor within an enclosure. Liquid spray manifolds have one or more spray nozzles that spray at an angle toward or away from the direction of rotation of the rotor, or an angle up or down, rather than straight at the boxes in the box holder assemblies. Improved spray coverage and cleaning is achieved.